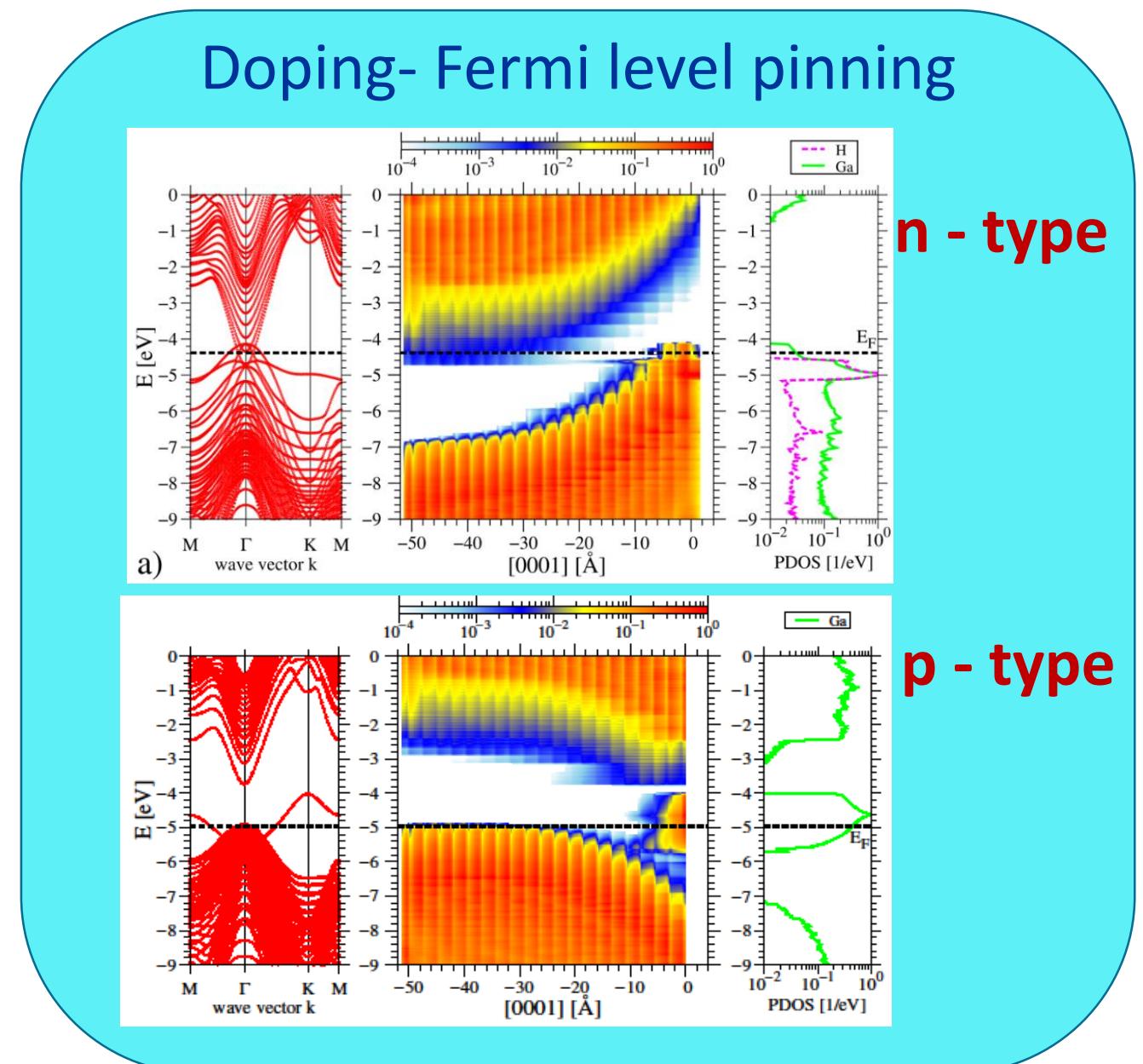
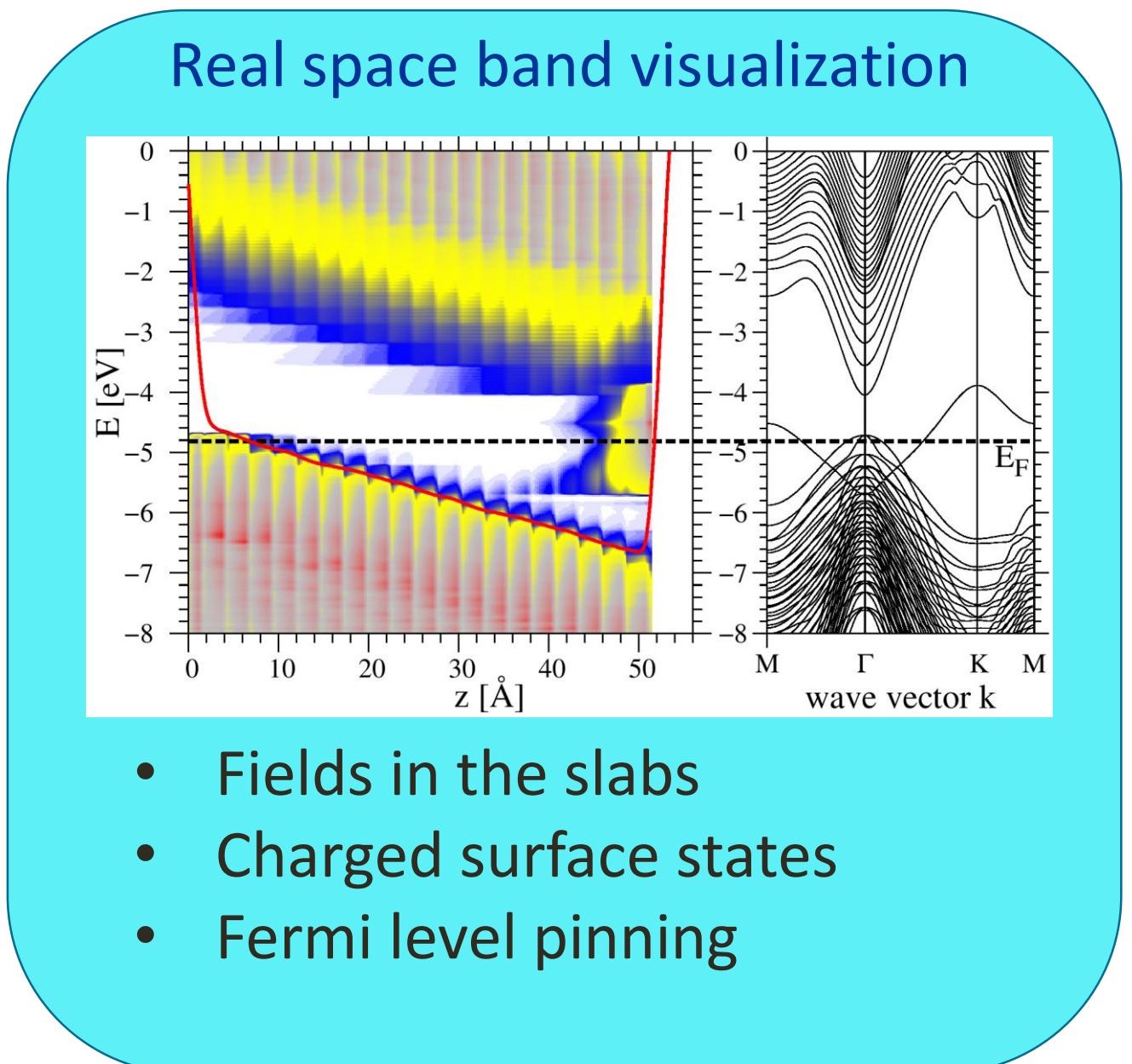
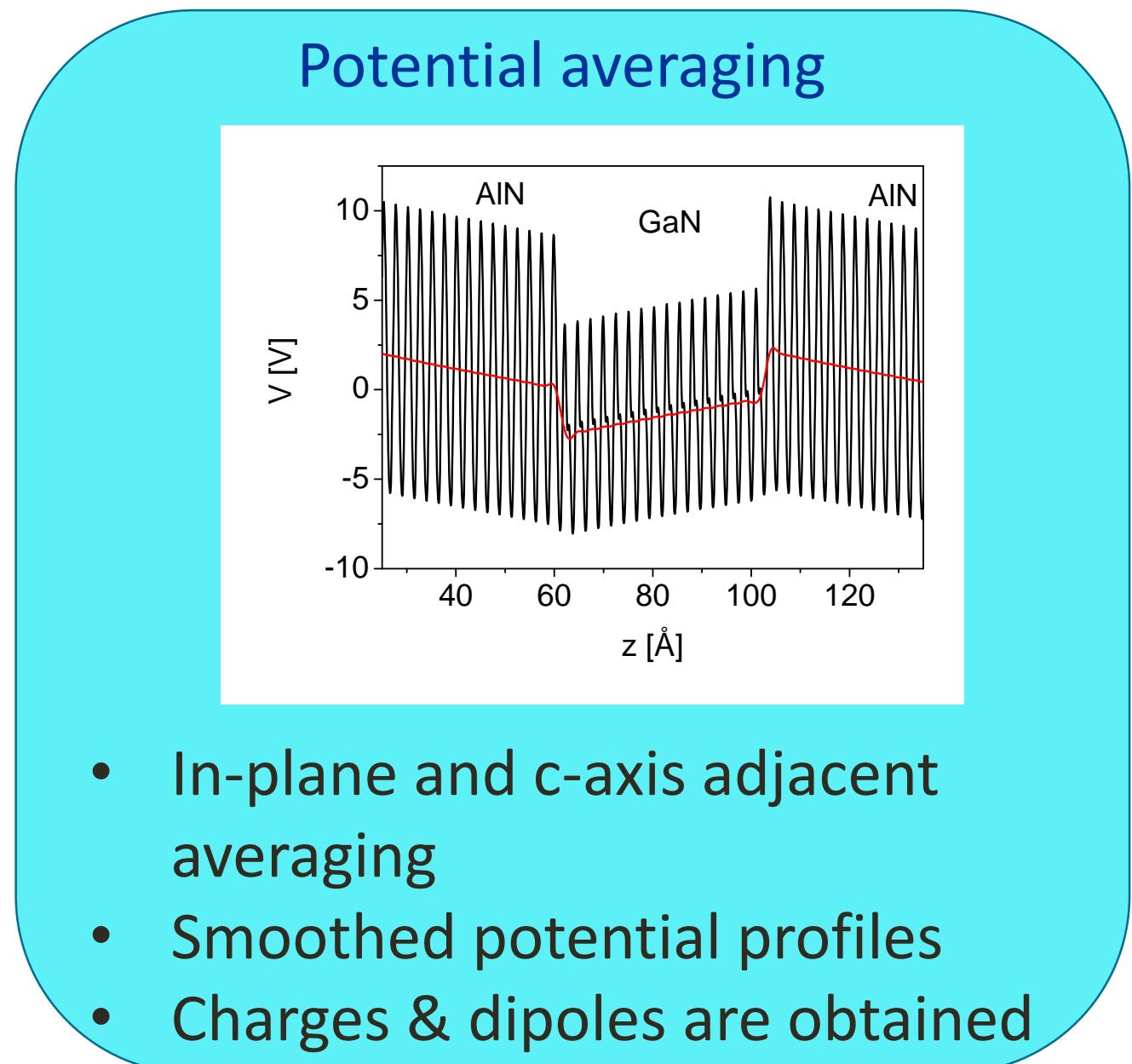
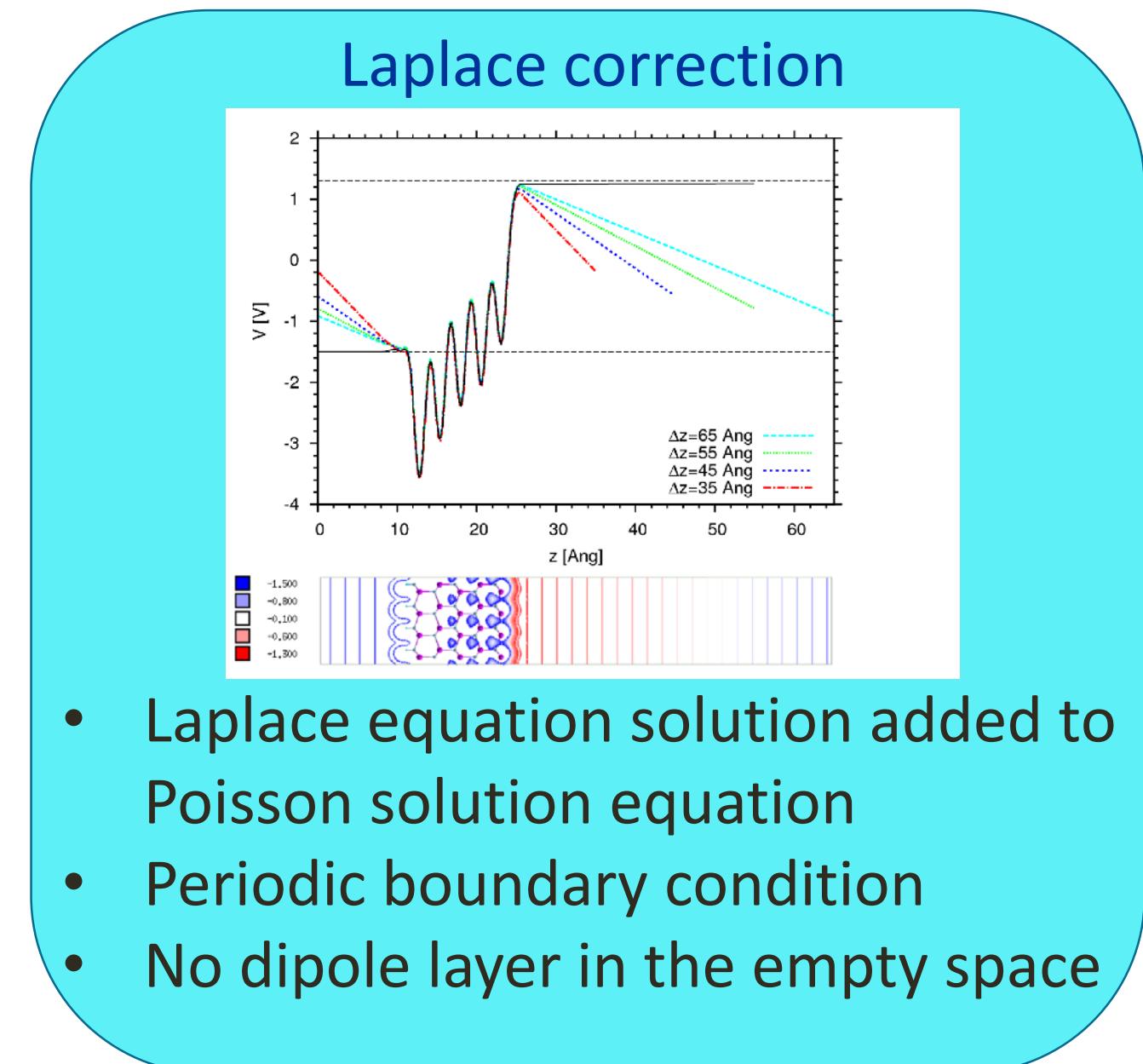


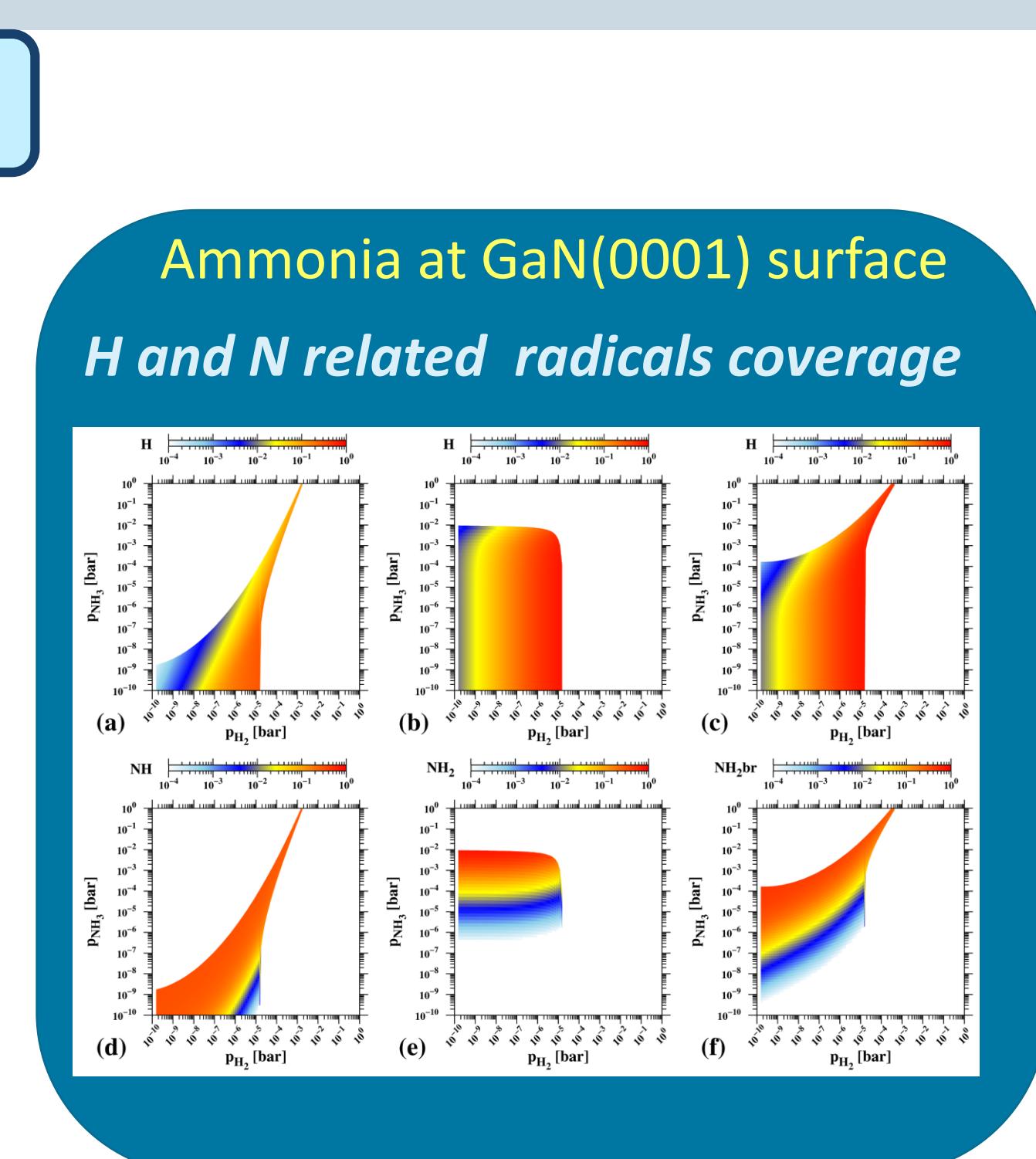
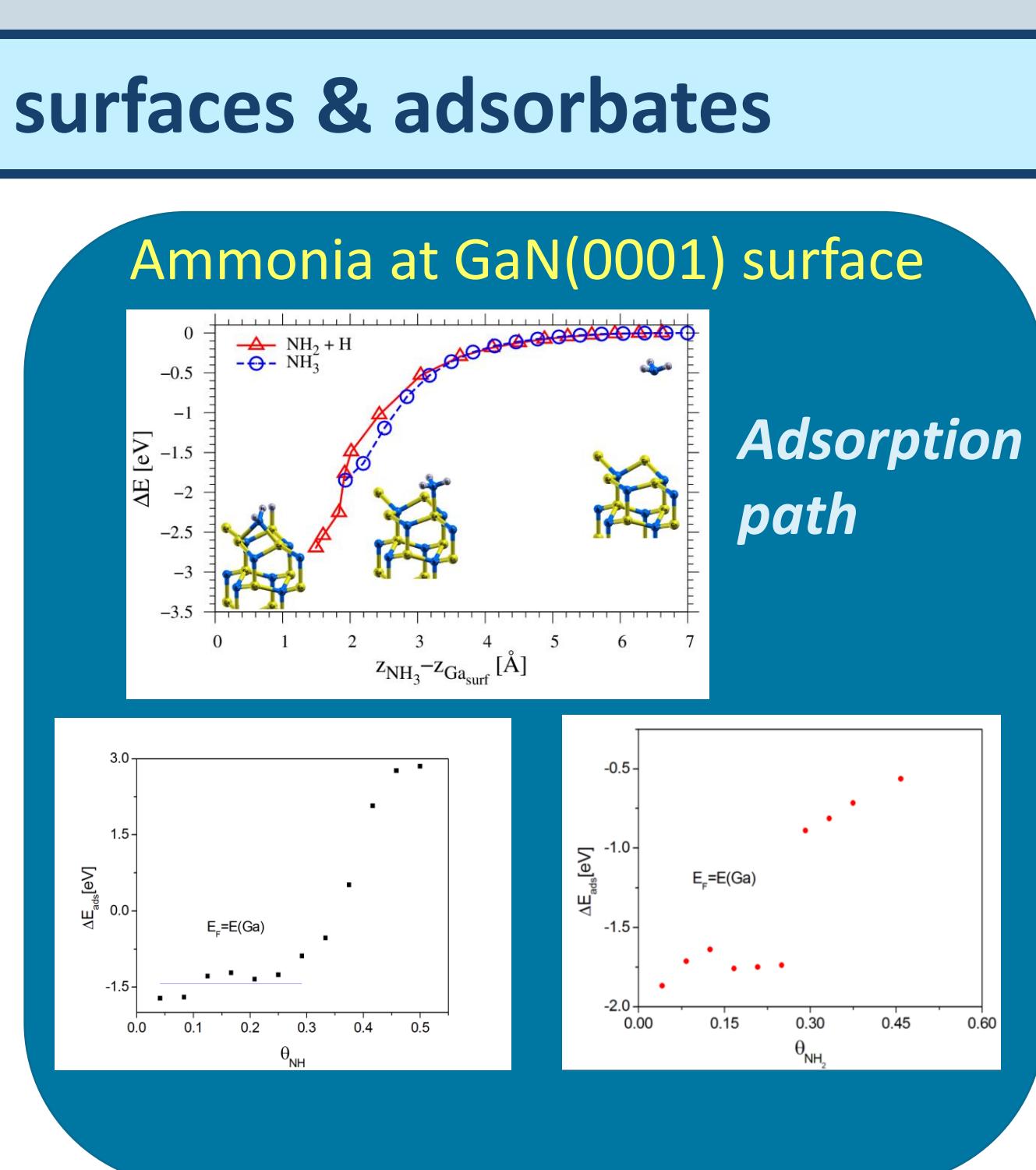
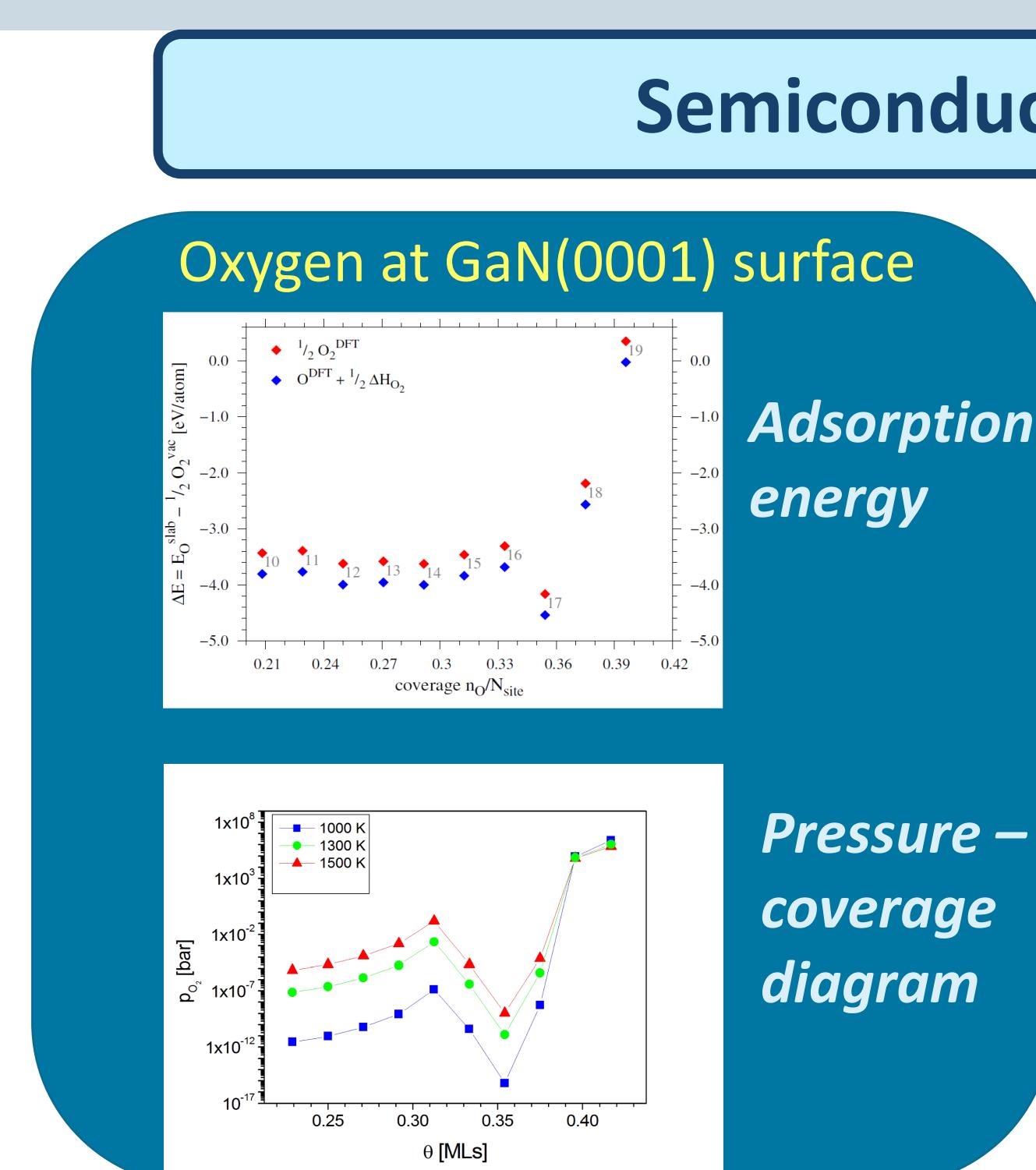
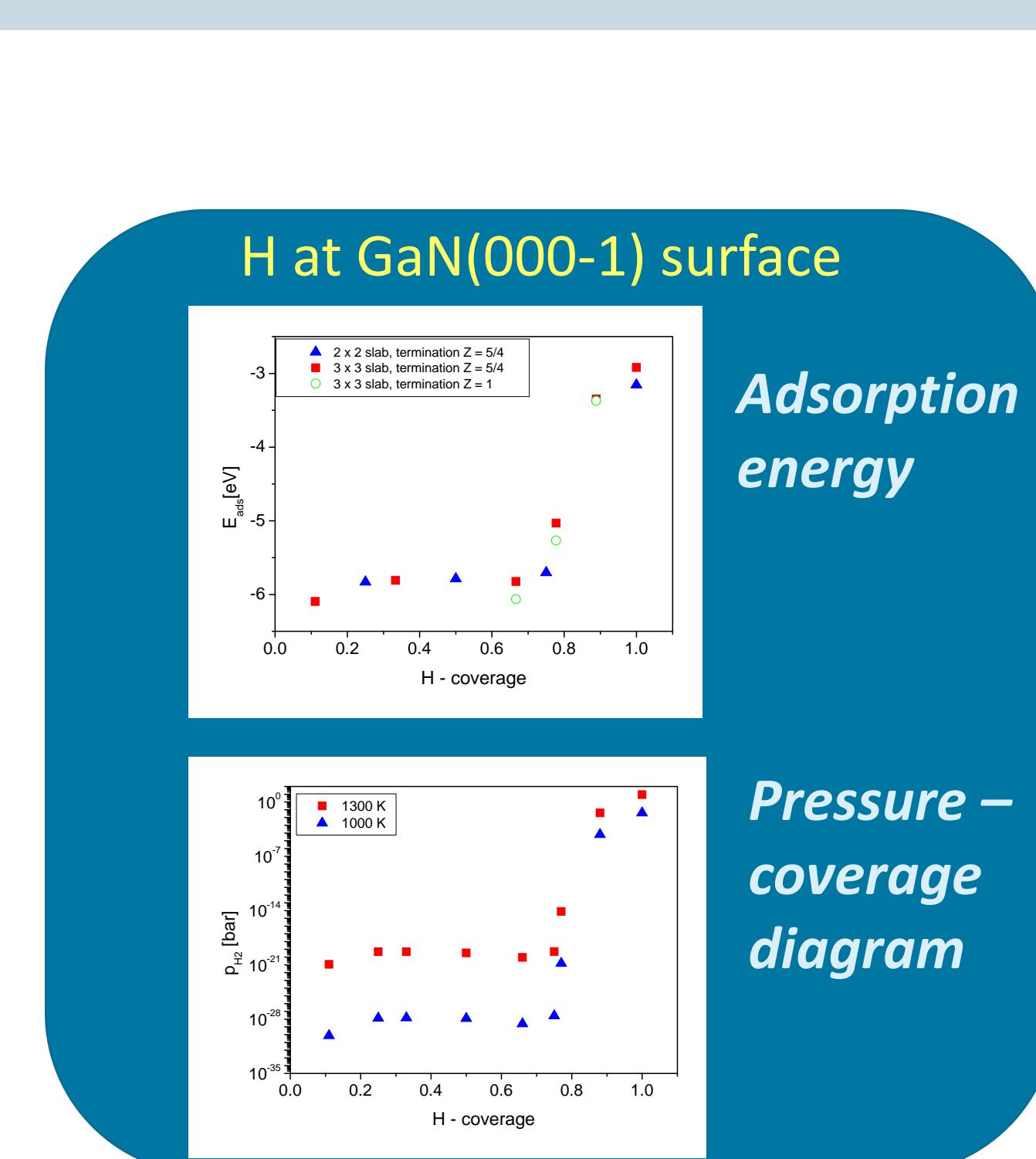
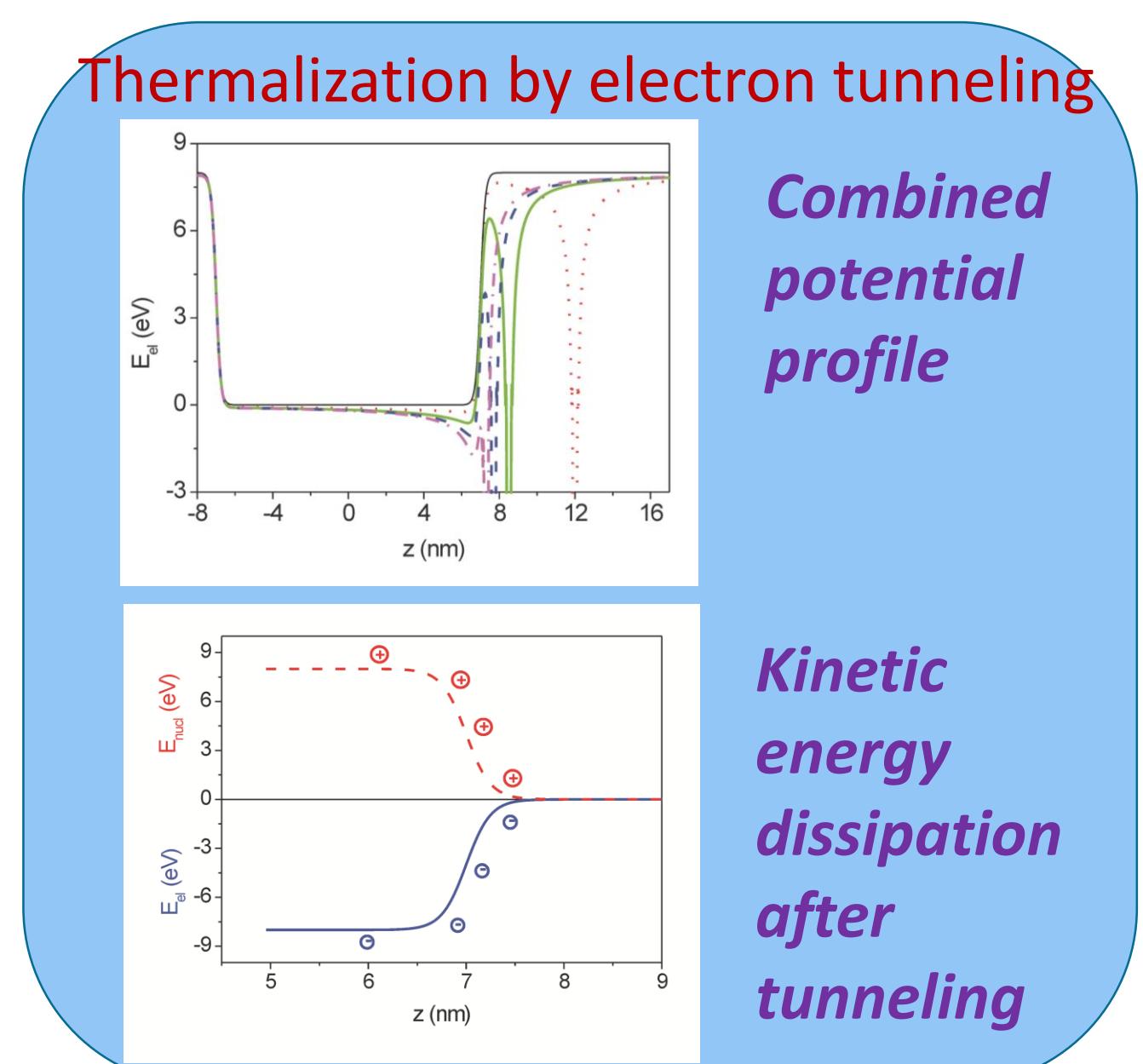
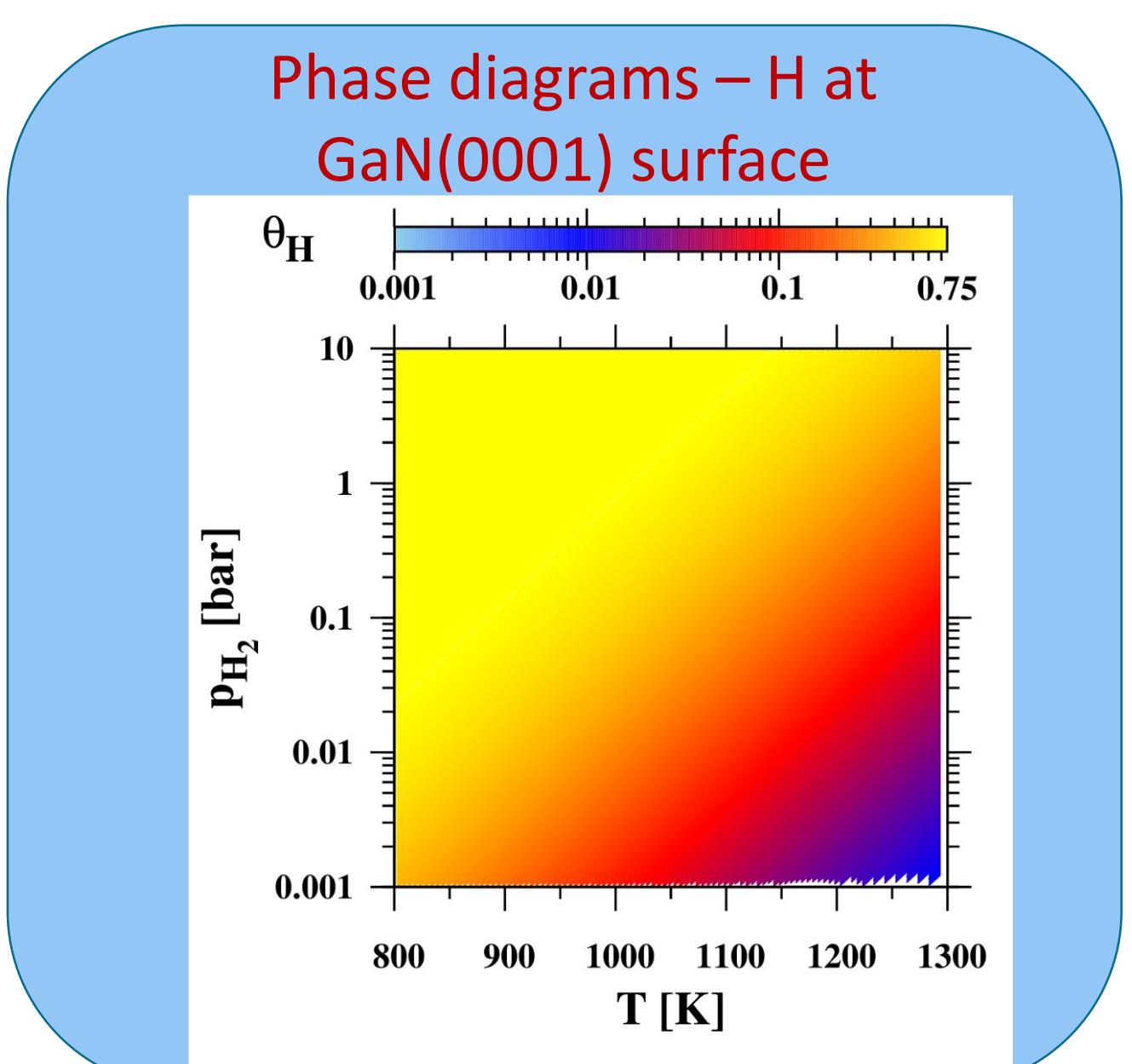
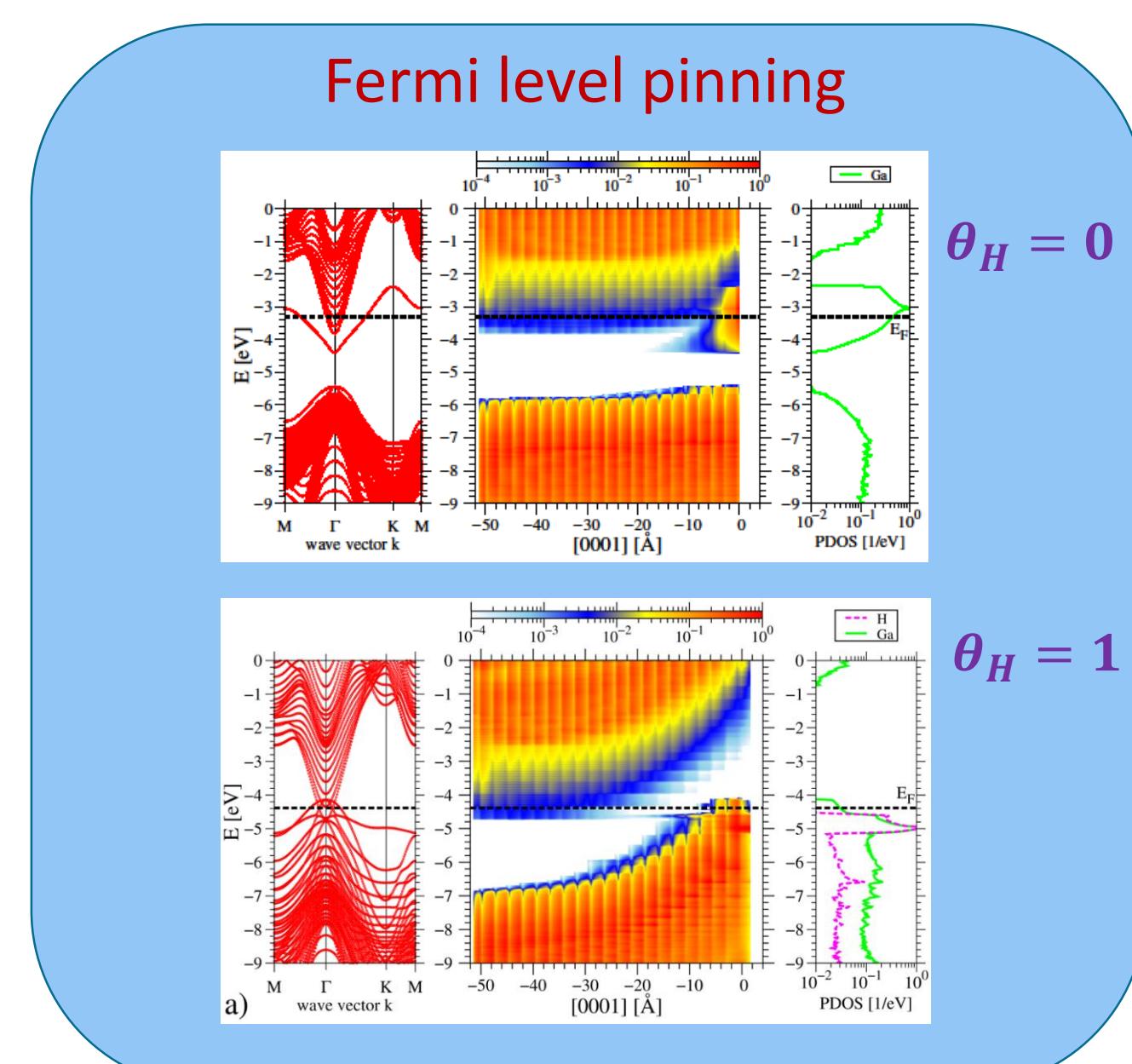
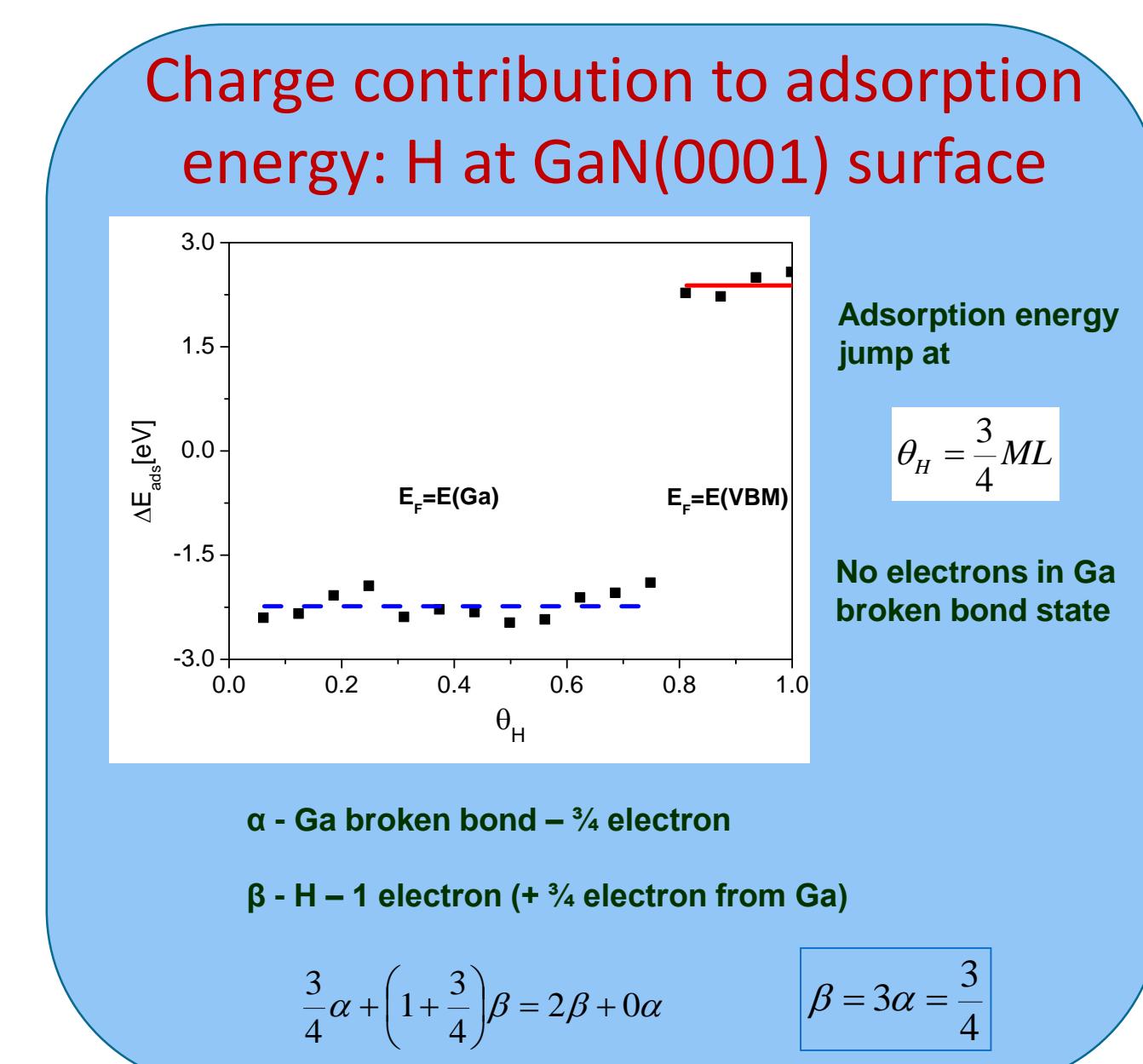
# Charge related phenomena at semiconductor surfaces

P. Strak, P. Kempisty, K. Sakowski, J. Sołtys, J. Piechota, M. Ptasińska, and S. Krukowski

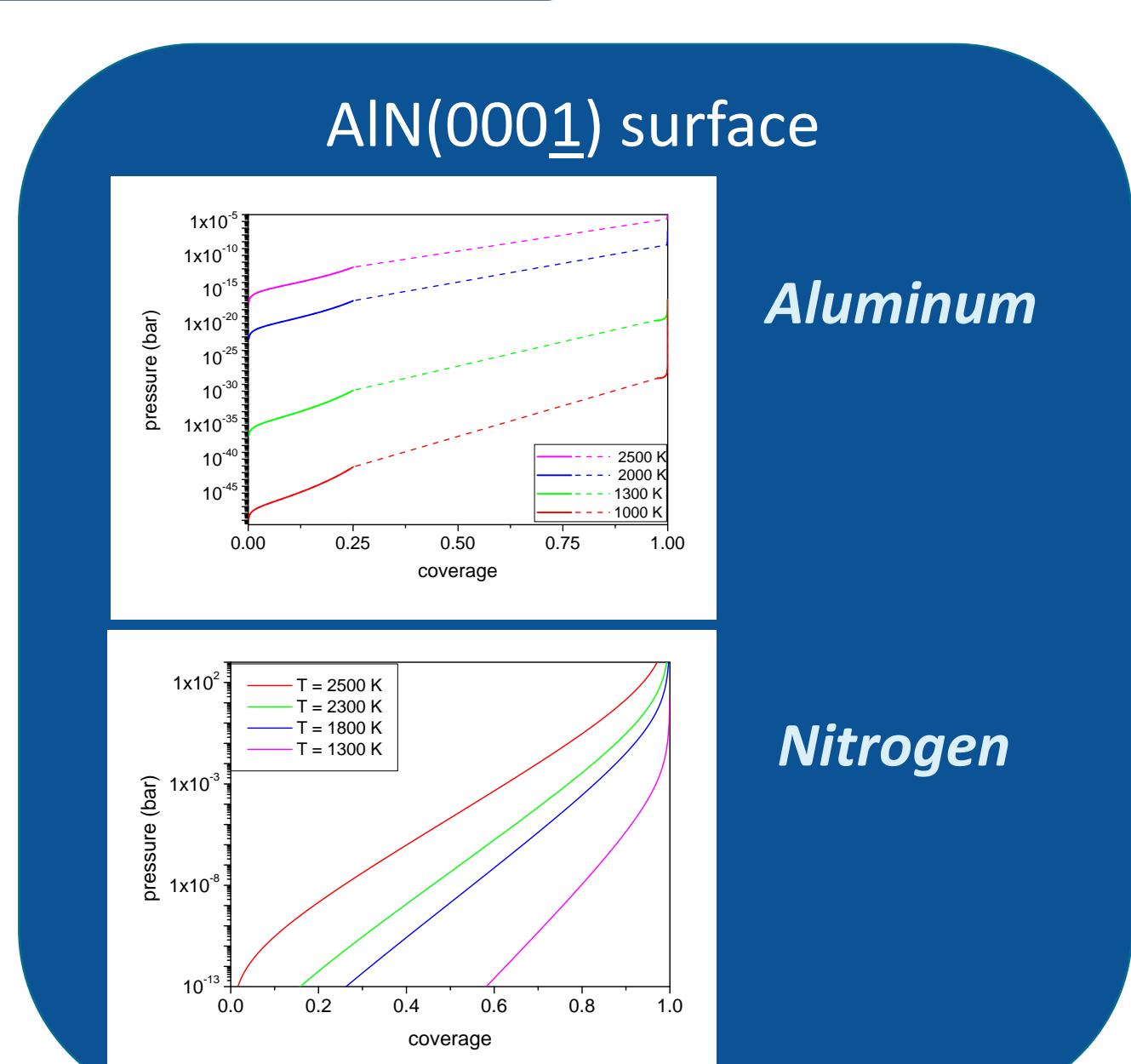
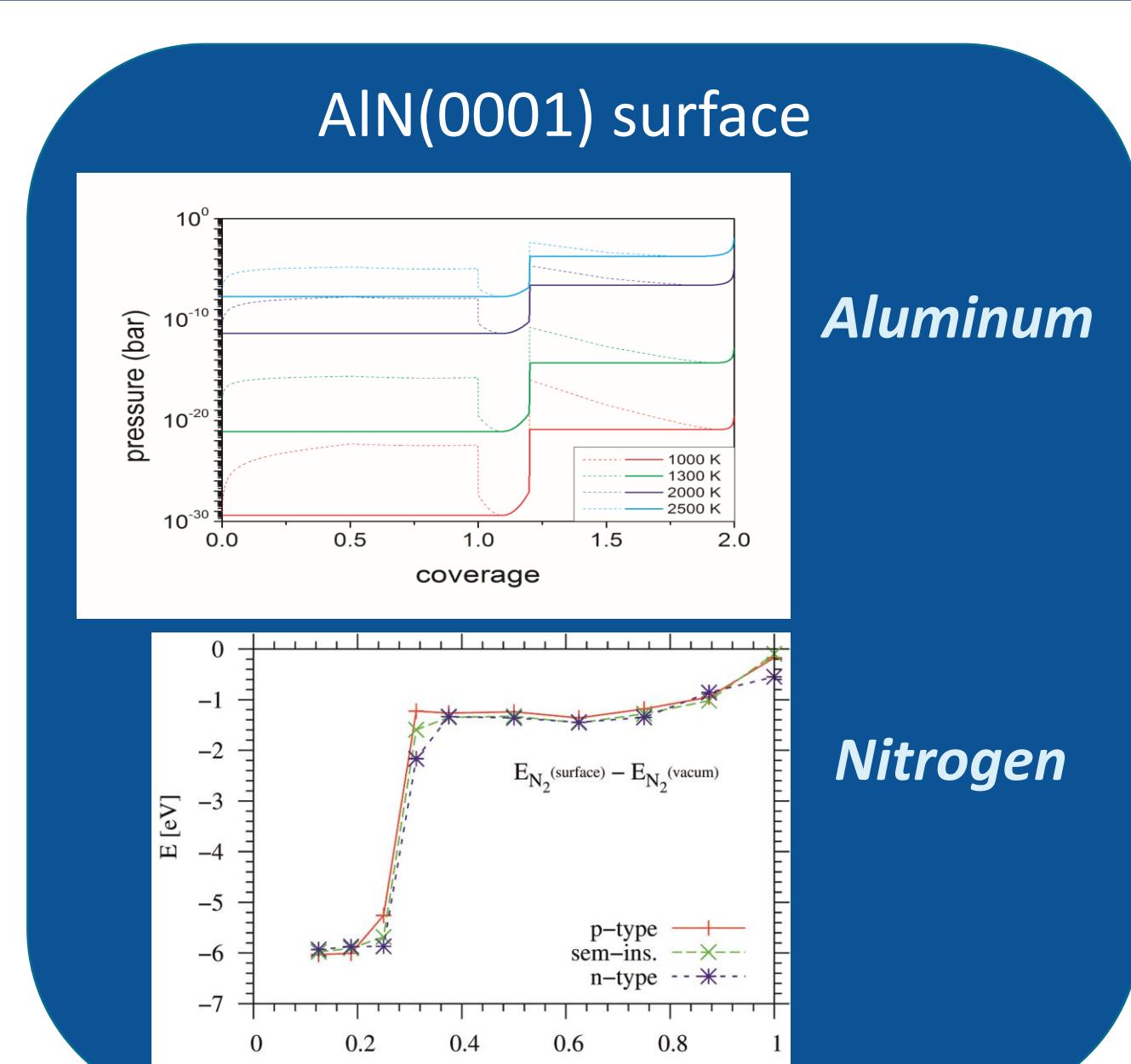
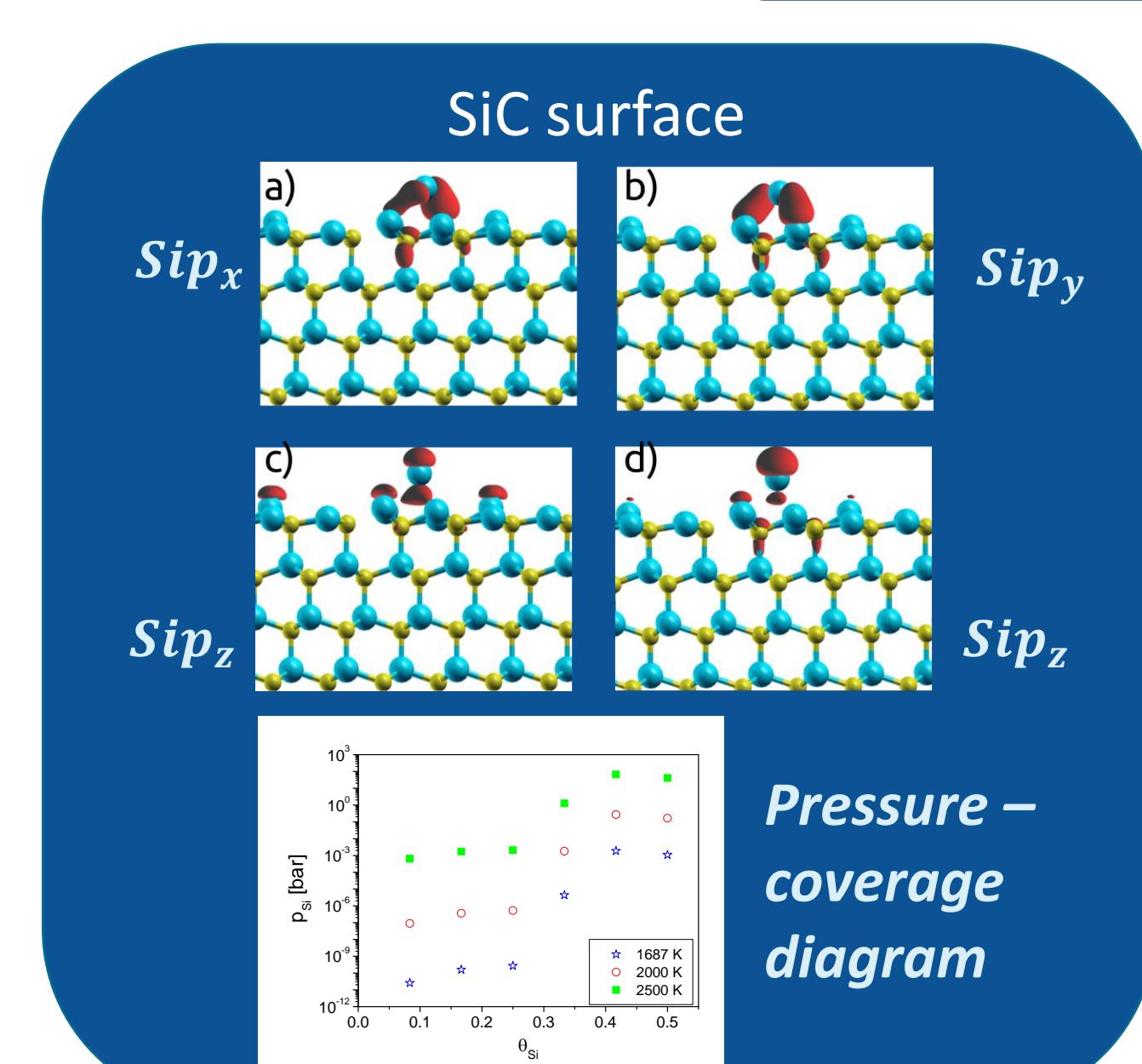
## New methodology – *ab initio* calculations (SIESTA & VASP)



## New results



## Semiconductor surfaces & adsorbates



- Laplace correction for slab simulations
- Averaging procedures for *ab initio* data
- Doping in surface slab simulations
- Charge transfer contribution to adsorption energy
- Adsorbate thermalization model
- Thermal contribution to free energy of the adsorbate
- Pressure-coverage diagrams for number of semiconductor surfaces

Use this QR code to see the poster on-line

